

FIGURE 1

0944303.4600

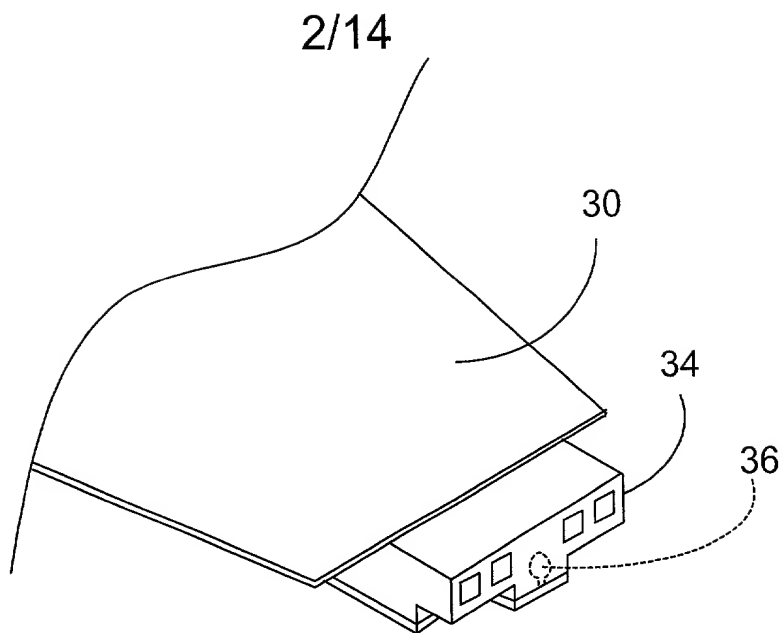


FIGURE 2

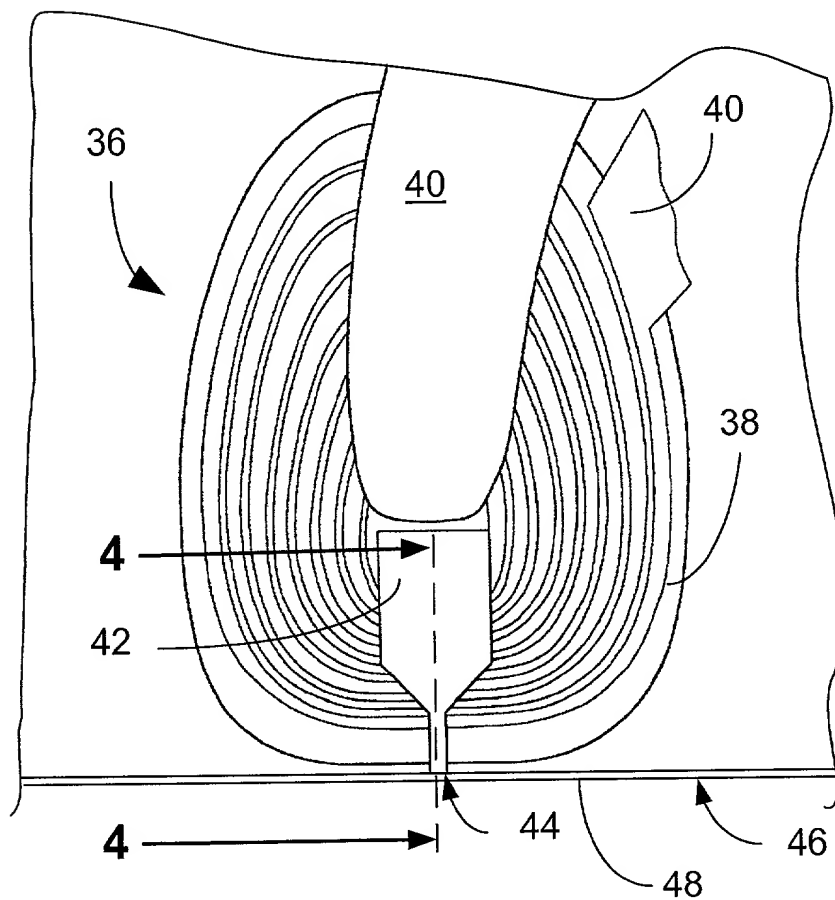


FIGURE 3





# FIGURE 4 (Prior Art)

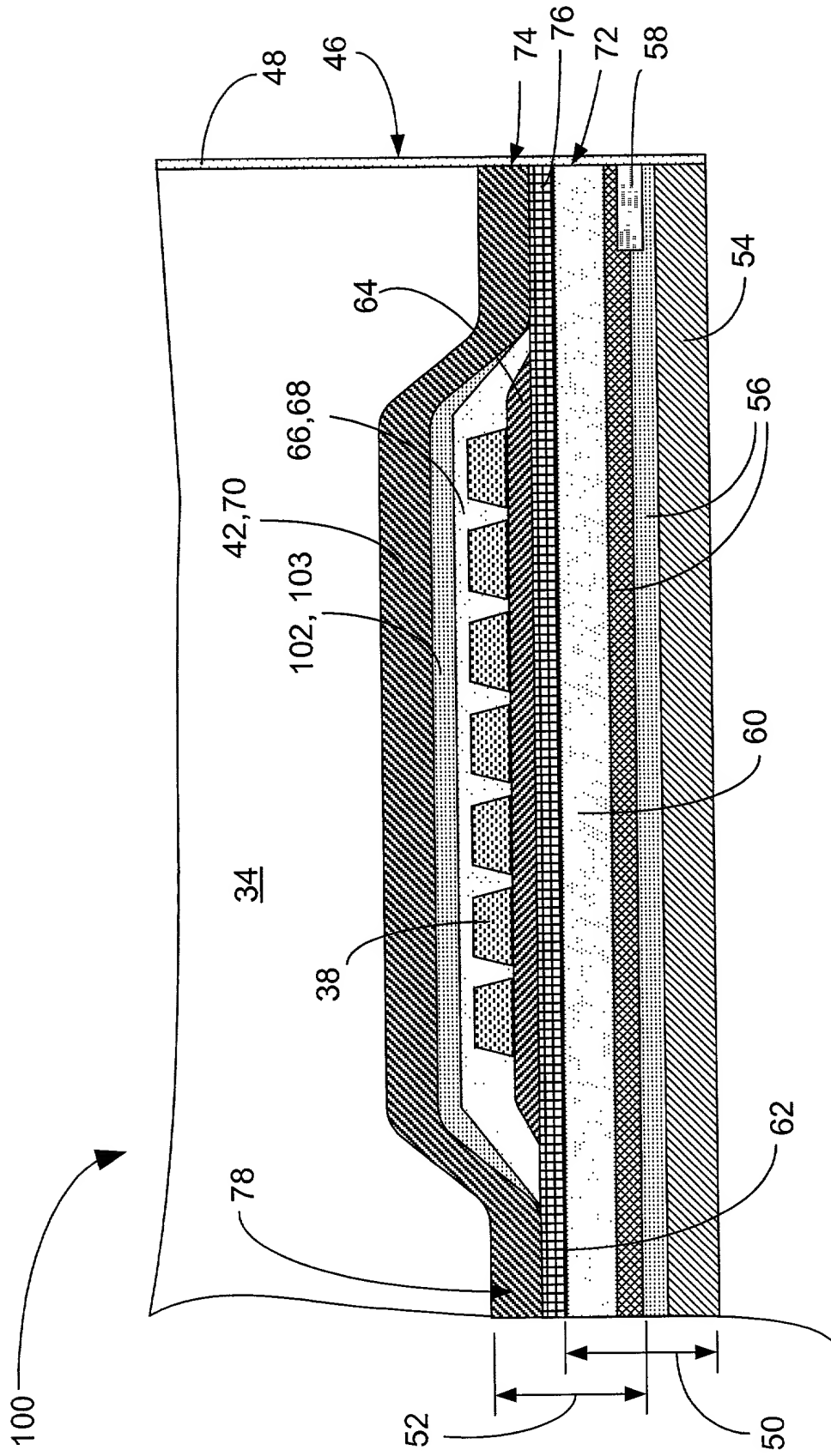


FIGURE 5



# FIGURE 6

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Composition	Substrate	Process	H <sub>k</sub> (Oe)	H <sub>th</sub> (Oe)	H <sub>be</sub> (Oe)	Easy axis
NFe19	Directly on I2	DC	4.60	0.06	1.26	OK
	Glass	DC	3.97	0.07	1.38	OK
NFe35	Directly on I2	DC	4.87	1.13	3.20	OK
	Glass	DC	17.08	0.85	2.24	OK
NFe45	Directly on I2	RF	23.00	1.85	10.53	Rotated 85 deg
	Glass	RF	5.92	1.25	4.86	OK
NFe55	Directly on I2	DC	Isotropic	14.11	18.10	Isotropic
	On I2 with SiO <sub>2</sub> shell	DC	7.11	0.77	4.45	OK
	Glass	DC	10.14	1.18	7.62	OK
	Directly on I2	RF	11.71	2.16	11.32	OK
	On I2 with SiO <sub>2</sub> shell	RF	9.37	1.10	7.10	OK
	Glass	RF	10.4	0.86	6.88	OK

FIGURE 7

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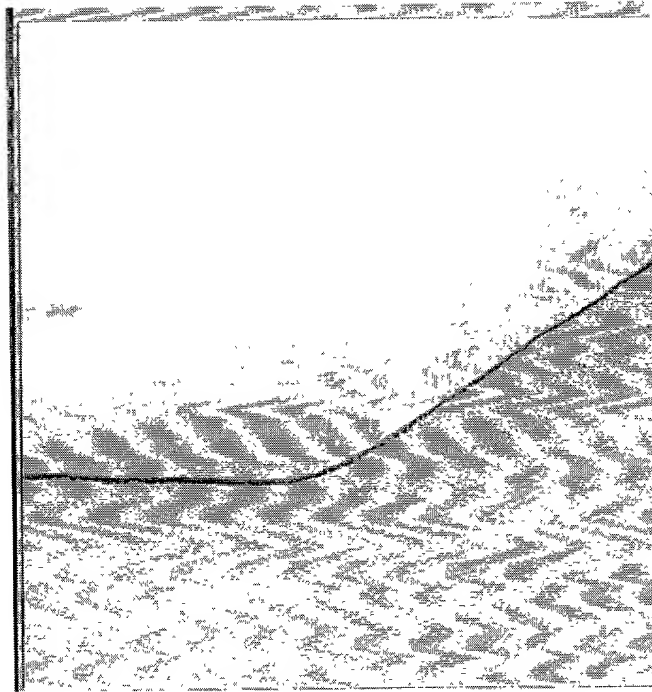


FIGURE 8

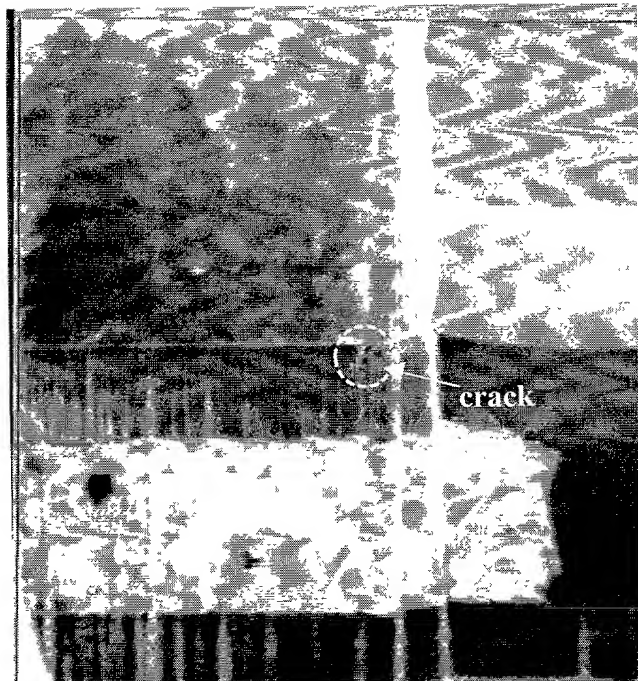


FIGURE 9

09745708-123400

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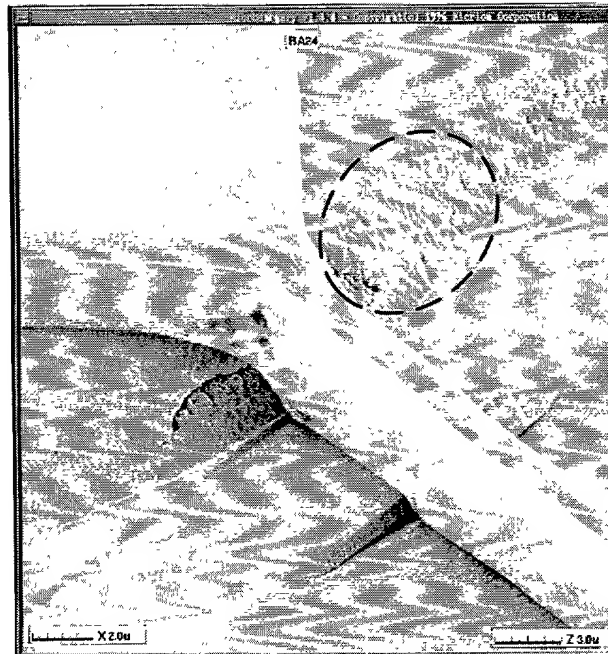


FIGURE 10

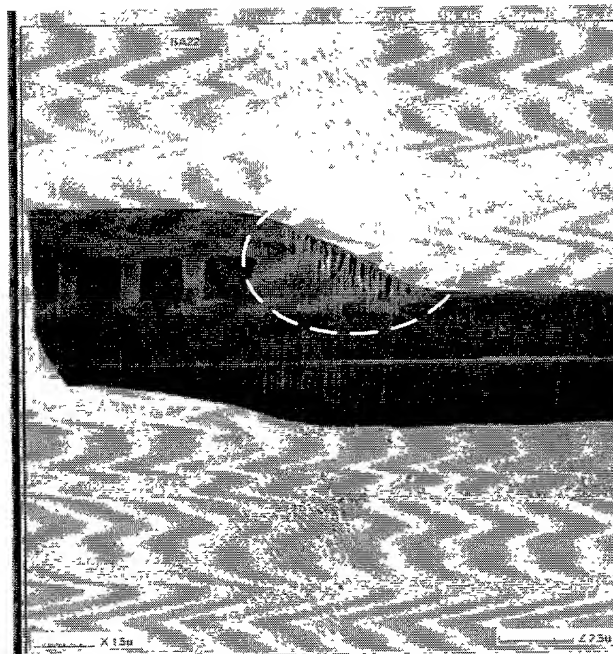


FIGURE 11

0974508-133100



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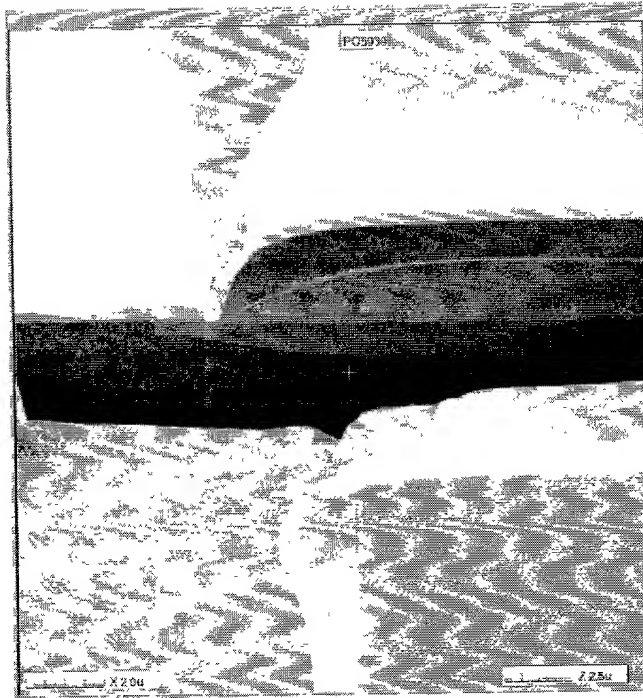


FIGURE 12

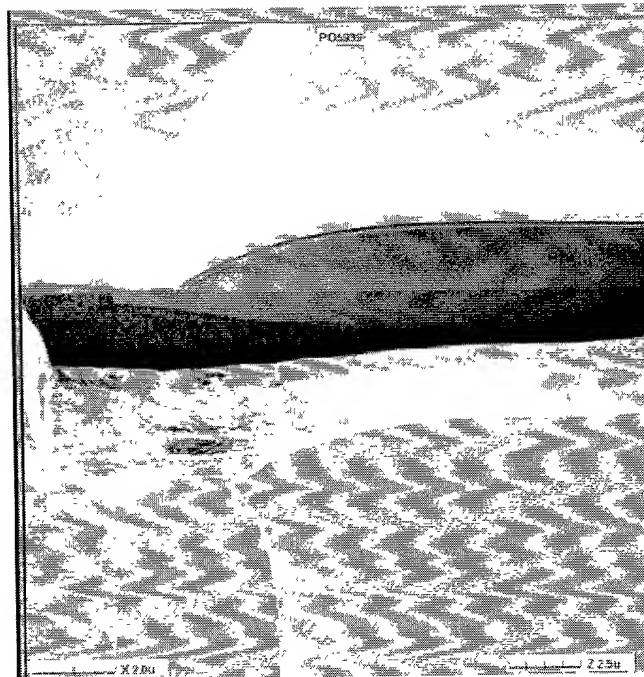


FIGURE 13

001221" 80454260

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001.221" 80/54/250

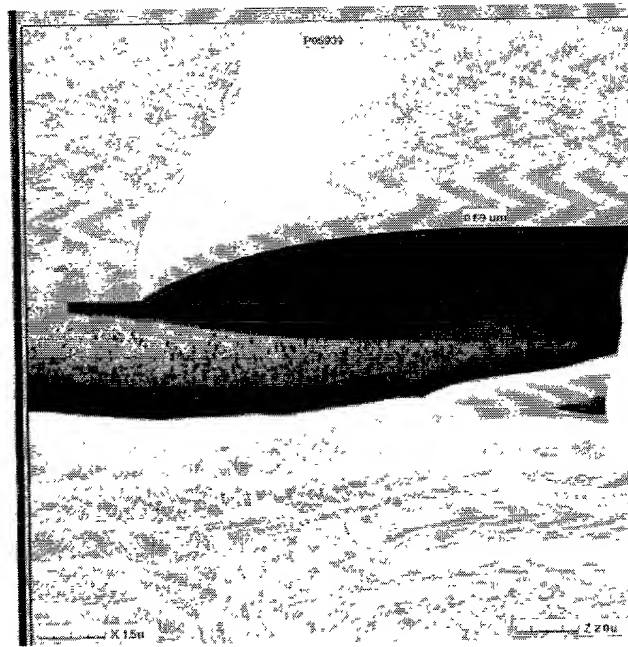


FIGURE 14

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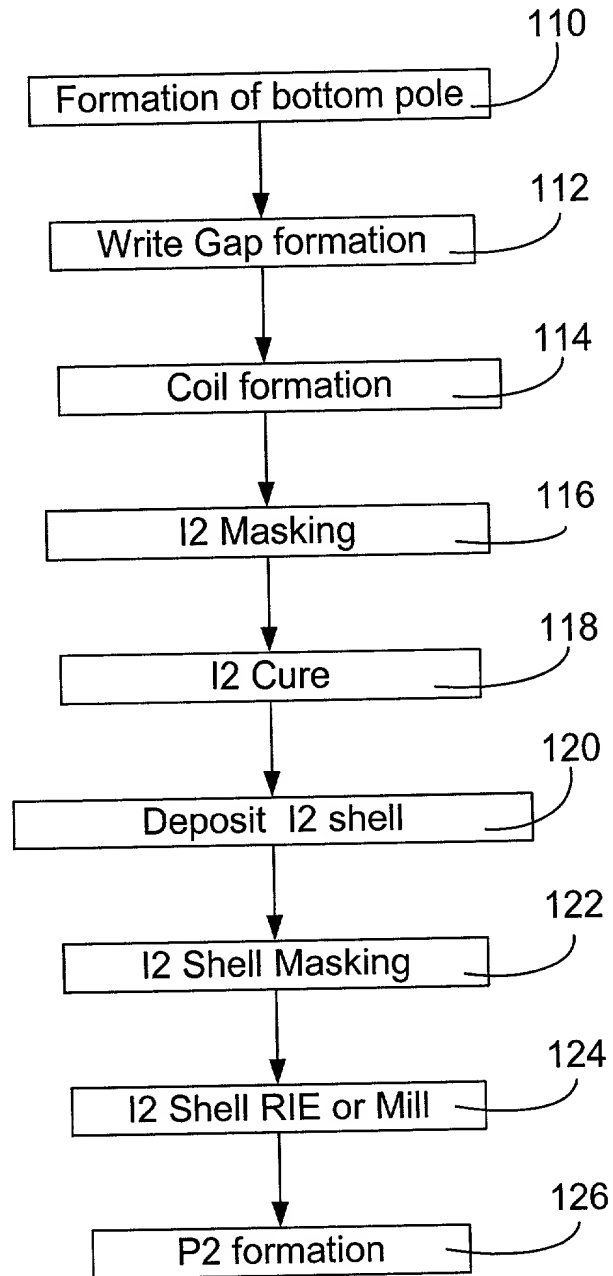


FIGURE 15

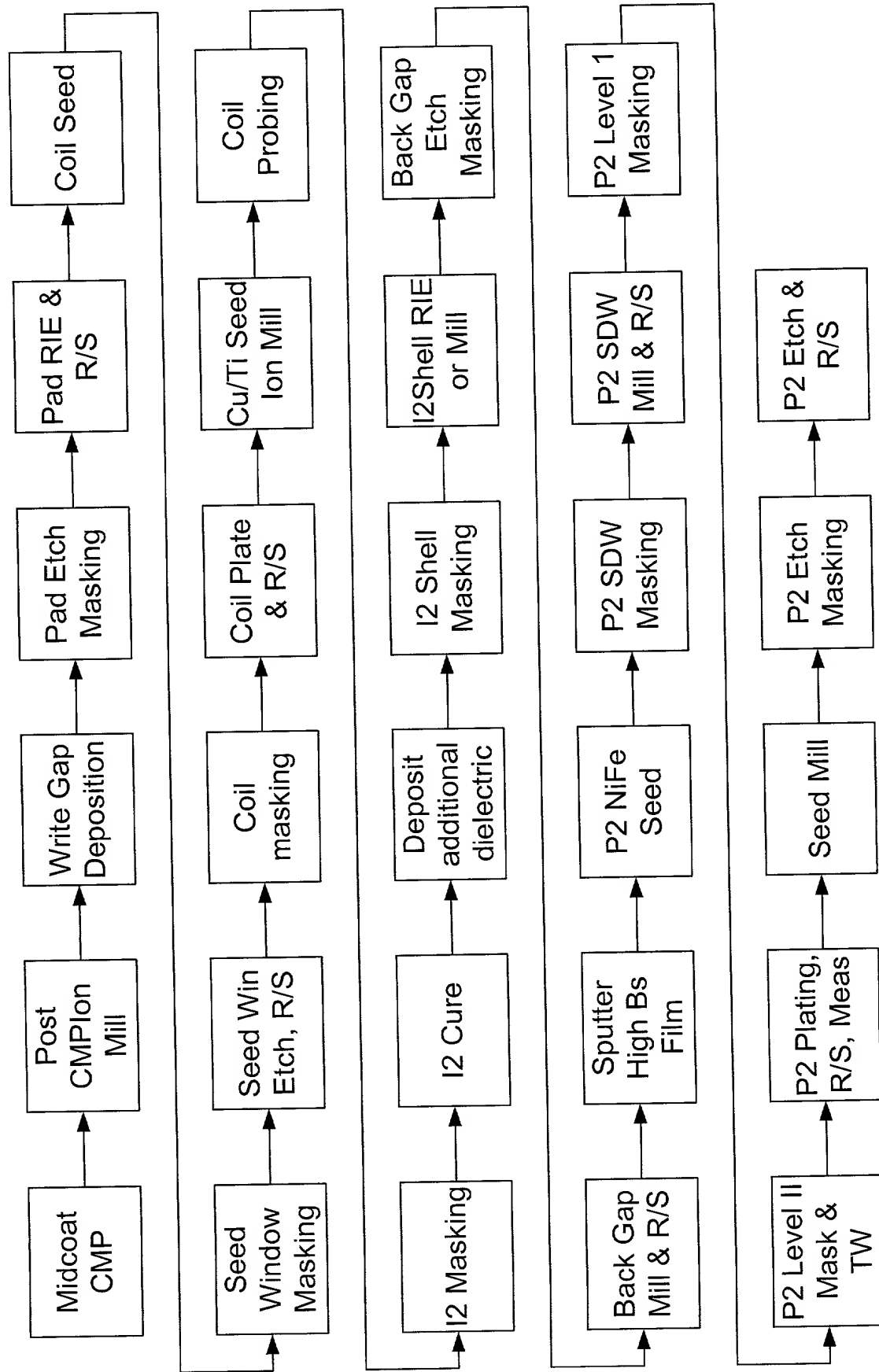


FIGURE 16

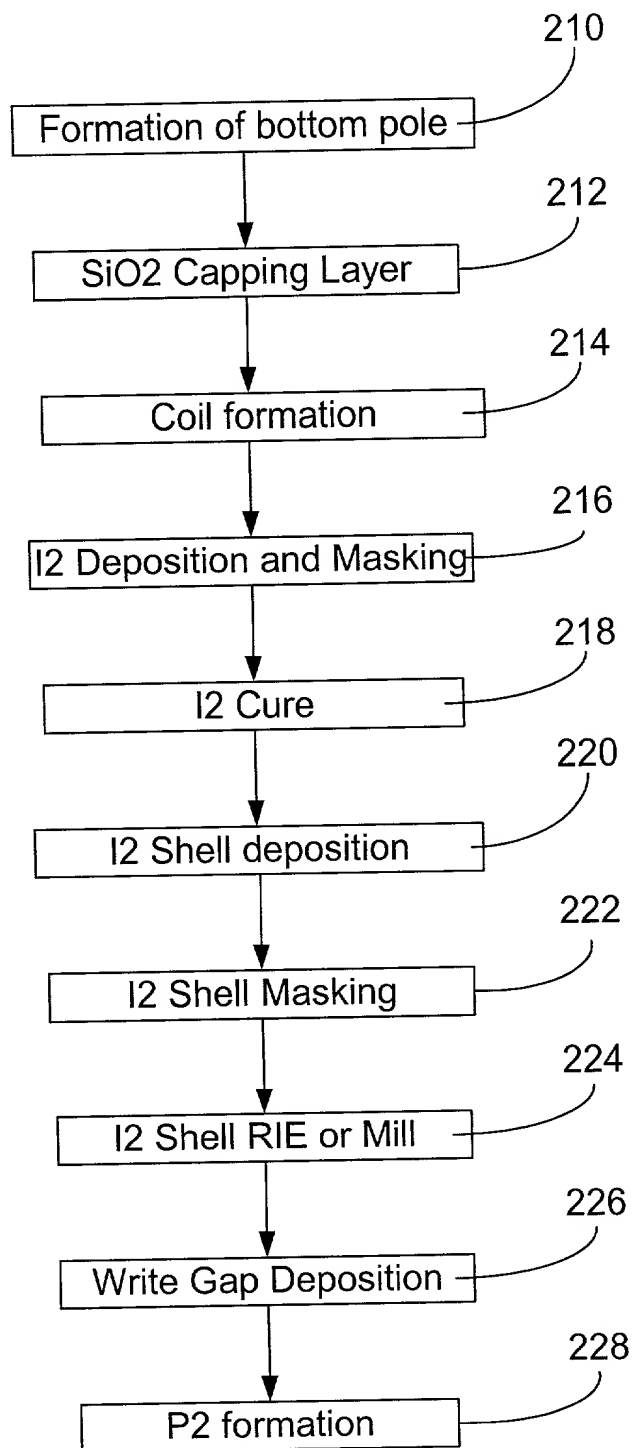


FIGURE 17

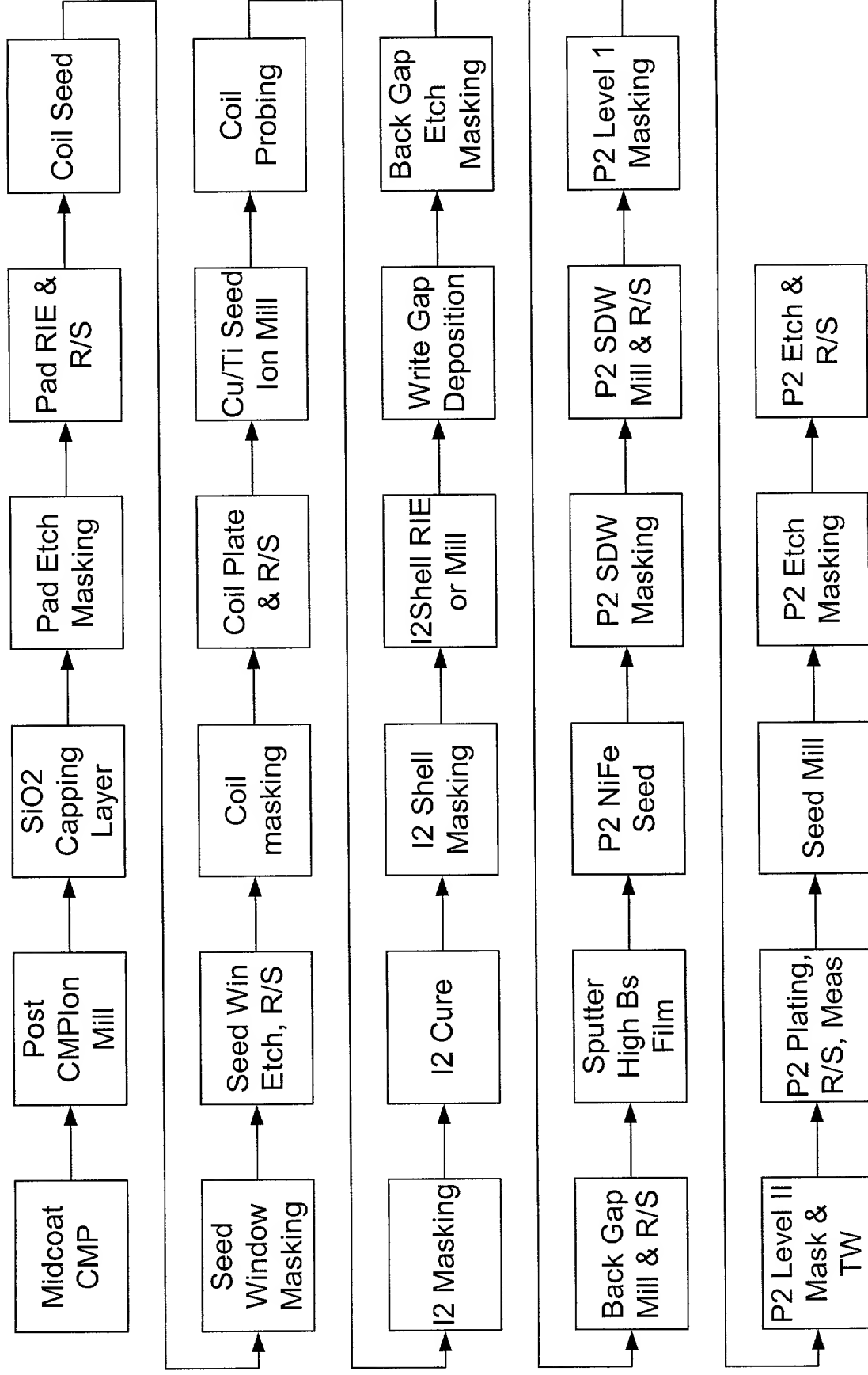


FIGURE 18